

Patent Abstracts of Japan

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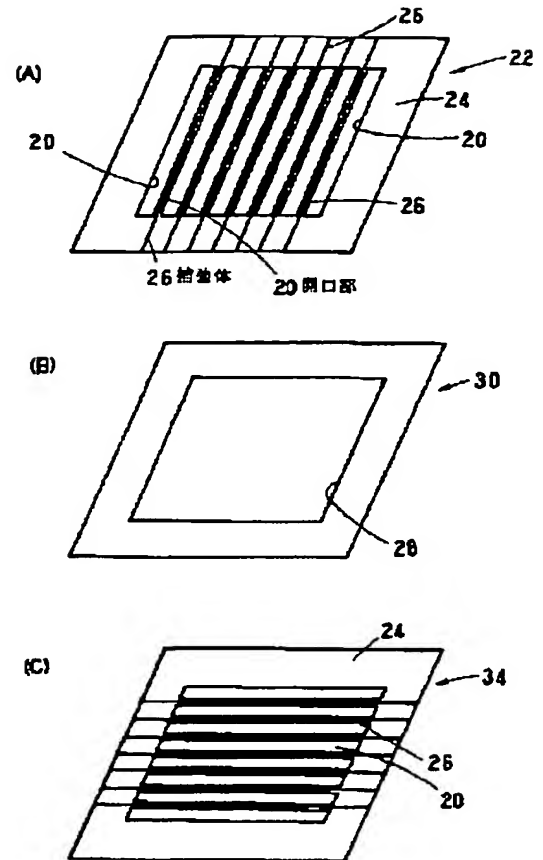
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APPLICANT : HOKURIKU ELECTRIC IND CO LTD;

INVENTOR : TANPO TETSUYA;

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TITLE : MASK FOR VAPOR DEPOSITION



ABSTRACT : PROBLEM TO BE SOLVED: To obtain a mask for vapor deposition having a simple structure and enabling the precise formation of a thin film such as a transparent electrode.

SOLUTION: The mask for vapor deposition has striped openings 20 for forming a transparent electrode on the surface of a transparent substrate of glass, a resin or the like with a transparent electrode material such as ITO so that the electrode is made striped at a prescribed pitch and has reinforcing bodies 26 which prevent the slack of the mask on the mask forming parts each between the openings 20.

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